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BIB DATA SHEET

CONFIRMATION NO. 8987

10/578,369	SERIAL NUM	BER	FILING		(1(c) CLASS		GR	GROUP ART UNIT			ATTORNEY DOCKET NO.	
APPLICANTS Syo-ichi Takamizawa, Annaka-shi, JAPAN; Ryuji Sayama, Annaka-shi, JAPAN; Ryuji Sayama, Annaka-shi, JAPAN; *** CONTINUING DATA ****This application is a 371 of PCT/JP04/12179 08/25/2004 ***FOREIGN APPLICATIONS ************************************	10/578,36	10/570 000				438		1792				
Syo-ichi Takamizawa, Annaka-shi, JAPAN; Ryuji Sayama, Annaka-shi, JAPAN; Ryuji Sayama, Annaka-shi, JAPAN; *** CONTINUING DATA **********************************	RULE			E								
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JAPAN 2003-385333 11/14/2003 ** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 11/28/2006 Foreign Priority claimed												
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35 USC 119(a-d) conditions met 2 Yes \(\) No Verified and Acknowledged (BOB M KUNEMUND) Acknowl												
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